

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-583002	Application No. 10/718,832
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Y. Long He et al.	
		Filing Date November 21, 2003	Group Art Unit 1763

(37 CFR §1.98(b))

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
IN	AA	5,843,847	12/01/1998	Pu et al.			
IN	AB	6,436,812	8/20/2002	Lee			
IN	AC	2002 / 0132488	9/19/2002	Nallan			
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
IN	AJ	61-171127	8/1/1986	Japan (English abstract only)				
	AK							
	AL							
	AM							
	AN							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
IN	AO	M. Oda et al. "Xray mask fabrication technology for...". Journal of Vacuum Science & Technology B 14(6):4366-4370, Nov-Dec. 1996.
IN	AP	P. E. Riley et al. "Implementation of Tungsten Metallization In Multilevel Interconnection Technologies". IEEE Transactions on Semiconductor Manufacturing 3(4): 150-157, November 1990.
	AQ	
	AR	

Examiner Signature IN	Date Considered 11/21/05
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	